

**DESIGN AND DEVELOPMENT OF A CMOS  
COMPATIBLE BULK MICROMACHINED  
ACCELEROMETER**

*Thesis submitted to  
Indian Institute of Technology, Kharagpur  
for the award of the degree*

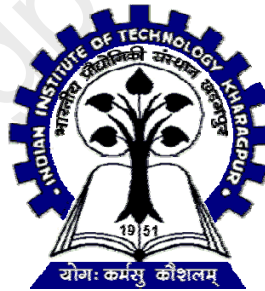
*of*

**Doctor of Philosophy**

*by*

**Ravindra Mukhiya**

*under the guidance of*  
**Dr. Tarun K. Bhattacharyya**



**DEPARTMENT OF ELECTRONICS AND ELECTRICAL  
COMMUNICATION ENGINEERING  
INDIAN INSTITUTE OF TECHNOLOGY, KHARAGPUR  
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